



بِسْمِ اللَّهِ الرَّحْمَنِ الرَّحِيمِ



Segregation and Its Importance

Atomic Segregation

- For **low growth temperatures** (for example 600°C in AlGaAs/GaAs system), atoms have less chance to rearrange after burial under upcoming layers.
- However, due to the **surface mobility**, atoms can displace on the growing surface.
- **Higher growth temperature** leads to the increase of the surface mobility that can result in **smoother surface**; however, it also causes the so-called **surface segregation** that is the exchange between the sub-layer atoms with the impinging atoms on the growing surface.
- Several experimental and theoretical studies indicate that both group III and V atoms with **weaker bond** strength and **elastic energy** segregate to the surface.

• مهاجرت اتم ها به معنی جا به جایی اتم های بالک و سطح به صورت یک طرفه است.

• این پدیده با thermal intermixing که در دو جهت و در دماهای خیلی بالا اتفاق میفتد نباید اشتباه گرفته شود.

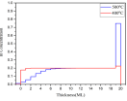
Atomic Segregation

- Heterojunctions between two given binary materials “A” and “B” are abrupt or not in composition, depending on the growth sequence (“A” grown on “B” or “B” grown on “A”).
- For one sequence (when one atom segregates), the top monolayer of the base material is gradually distributed in the growing over layer.
- For group III arsenide material, the segregation tendency can be summarized as $\text{In} > \text{Ga} > \text{Al}$.
- This means the surface composition of the ternary arsenide $\text{Ga}_{0.7}\text{Al}_{0.3}\text{As}$ is found to be Ga-rich and $\text{Ga}_{0.5}\text{In}_{0.5}\text{As}$ and $\text{Al}_{0.5}\text{In}_{0.5}\text{As}$ alloys to be In-rich.
- This should not get confused with thermal intermixing which is happening in both up and down growth directions and above 600°C for arsenide material.

Atomic Segregation

- For example, on the well-known **AlGaAs/GaAs** QW system, theoretical and experimental results show “**Ga**” segregation in AlGaAs layer that can cause a composition asymmetry at the normal interface for both AlGaAs/GaAs and GaAs/AlGaAs growths.
- The composition asymmetry at the interfaces results in the change of the **energy band** alignment of the quantum structures, which alters the **optoelectronic properties**.
- Therefore, to design an optoelectronic device based on the III-V semiconductor structures, it is important to **predict** and **compensate** the concentration profile change due to the segregating of atoms.
- Segregation may also prevent **dopant atoms** from getting correctly **incorporated** during the growth, or redistribute impurities like carbon.

Segregation Effects



- 1) Geometrical accuracy of the structure.
- 2) **Interface abruptness**: Considering segregation, for a binary heterostructure, the two interfaces behave differently as in one case we may see a ternary material while the other one will remain binary with no segregation.
- 3) **Energy bandgap deformation**.
- 4) **High doping level**: Segregation can lead to a very high doping level if the segregation atoms acts as dopants.
 - For example, if segregation of substrate atoms leaves 0.001 ML of substrate atoms to be incorporated in each growing monolayer, the supply is exhausted after a 0.3 μm growth, but the resulting over layer has a doping level of $3 \times 10^{19} \text{ cm}^{-3}$.

Periodic Table

1 H																	2 He						
3 Li	4 Be																	5 B	6 C	7 N	8 O	9 F	10 Ne
11 Na	12 Mg																	13 Al	14 Si	15 P	16 S	17 Cl	18 Ar
19 K	20 Ca	21 Sc	22 Ti	23 V	24 Cr	25 Mn	26 Fe	27 Co	28 Ni	29 Cu	30 Zn	31 Ga	32 Ge	33 As	34 Se	35 Br	36 Kr						
37 Rb	38 Sr	39 Y	40 Zr	41 Nb	42 Mo	43 Tc	44 Ru	45 Rh	46 Pd	47 Ag	48 Cd	49 In	50 Sn	51 Sb	52 Te	53 I	54 Xe						
55 Cs	56 Ba	71 Lu	72 Hf	73 Ta	74 W	75 Re	76 Os	77 Ir	78 Pt	79 Au	80 Hg	81 Tl	82 Pb	83 Bi	84 Po	85 At	86 Rn						
		57 La	58 Ce	59 Pr	60 Nd	61 Pm	62 Sm	63 Eu	64 Gd	65 Tb	66 Dy	67 Ho	68 Er	69 Tm	70 Yb								
		89 Ac	90 Th	91 Pa	92 U	93 Np	94 Pu	95 Am	96 Cm	97 Bk	98 Cf	99 Es	100 Fm	101 Md	102 No								

تمایل مهاجرت اتم ها

- برای اتم های گروه III تمایل مهاجرت به شکل زیر خلاصه می شود.

In>Ga>Al

- که همین ترتیب را در طول باند و Bonding-Energy نیز می توانیم مشاهده کنیم:

- Bonding Energy:

III-As Materials: In-As(1.41 eV) < Ga-As (1.59 eV) < Al-As (1.98 eV)

III-Sb Materials: Ga-Sb (1.50 eV) < Al-Sb(1.79 eV)

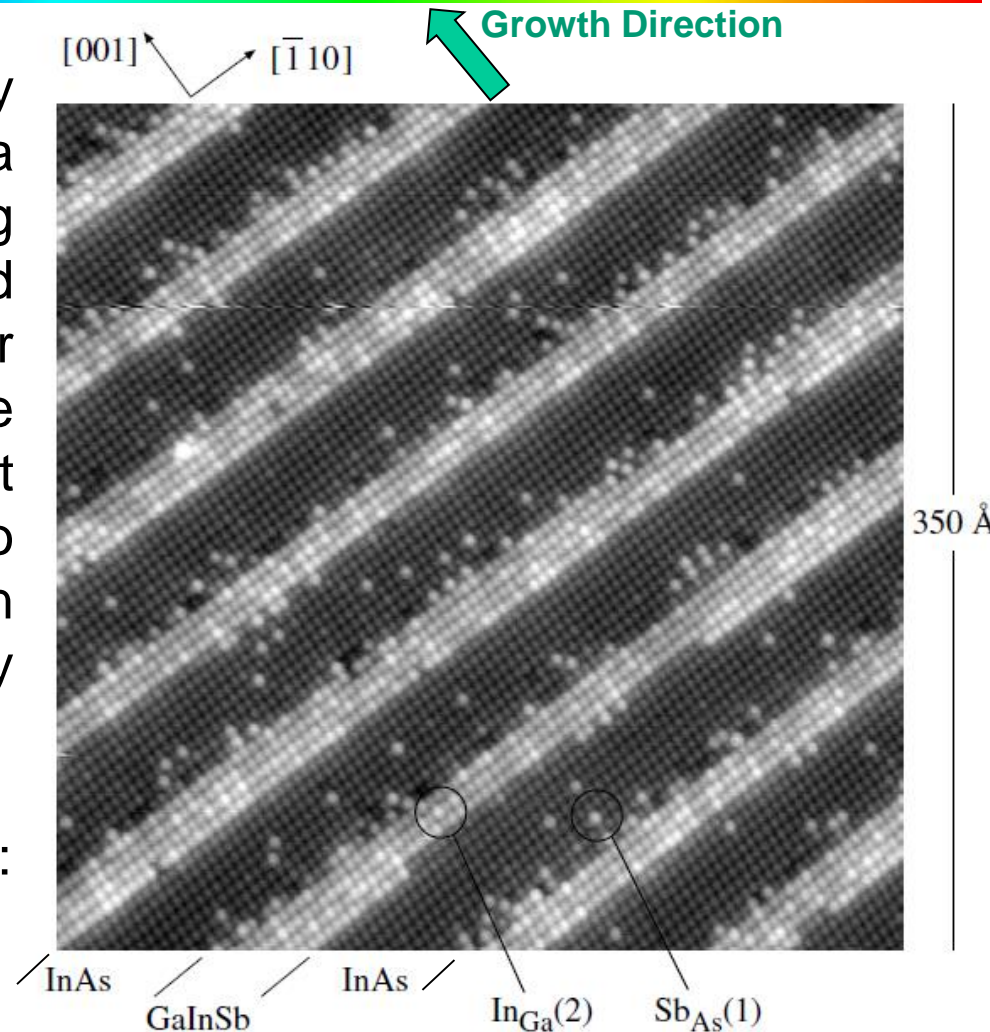
- Bonding Length:

III-As Materials: In-As(2.62 Å) > Ga-As (2.45 Å) ≈ Al-As(2.45 Å)

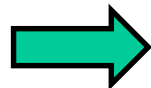
III-Sb Materials: Ga-Sb (2.64 Å) < Al-Sb (2.66 Å)

Segregation Realization in Type II SLS

- **Segregation** is an inherently asymmetric process that reflects a layer-by-layer competition, during growth, between strain- and/or bond – strength energies that favor expulsion of certain atoms to the surface and entropic factors that account for the tendency to nonetheless incorporate a fraction of these atoms in successively buried epitaxial layers.
- Type of Segregations in this sample:
 1. Sb Segregation
 2. In Segregation



Lattice disorder at interfaces



No interface abruptness



The Driving Force of Segregation

What Is The Driving Force for Segregation?

- Segregation is driven by:
 - 1- Difference in **binding energy**;
 - 2- Difference in **elastic energy**; which is the mechanical potential energy stored in the configuration of a material or physical system as it is subjected to elastic deformation by work performed upon it.
- Segregation in III-V compounds results in:
 - 1- Gradual **composition**.
 - 2- **Surface enrichment** of one of the incorporated group III elements.
 - 3- Energy **band structure deformation**.
 - 4- **Doping** level deformation.

Does Segregation Depend on The Growth Conditions?

- The profile of the segregating atom in the structure does change with the following growth parameters:

1) Growth Temperature (T_g) ↑

Segregation ↑

2) Growth Rate ↑

Segregation ↓

3) III/V Partial Pressure Ratio ↑

Segregation ↑

4) Growth Pressure ↑

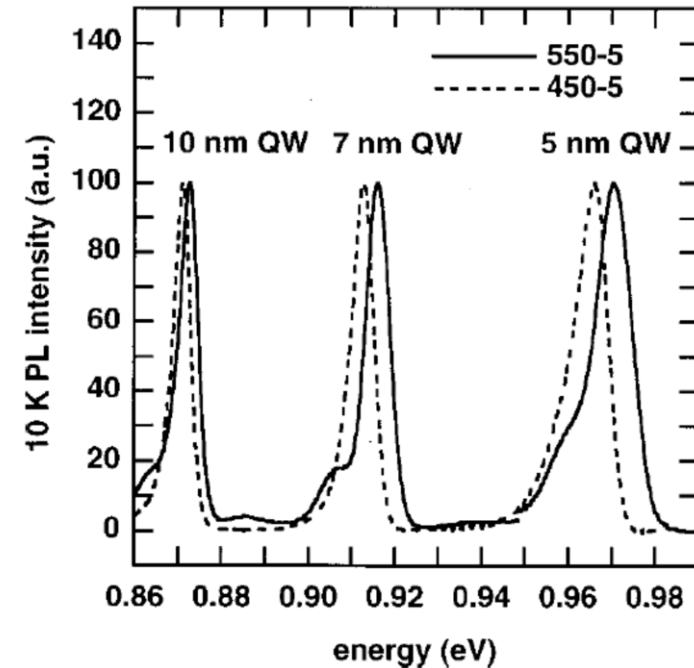
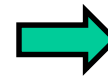
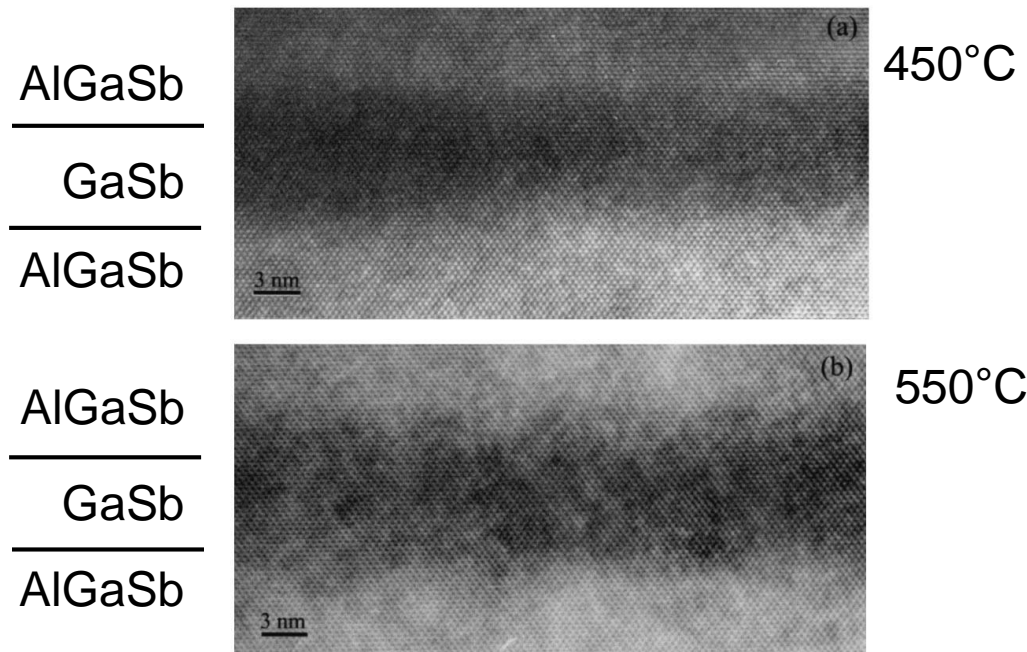
Segregation ↓

5) Interruption Time ↑

Segregation ↑

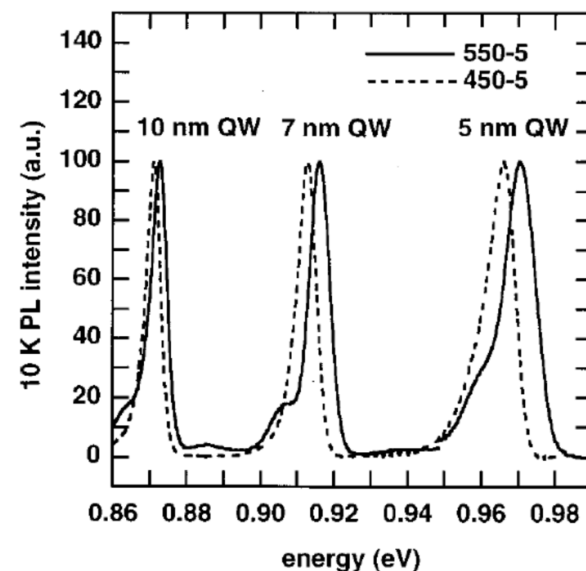
What are the influences of segregation on the characteristic properties of III-V structures?

- Composition of the grown layers changes \Rightarrow Band lineup of the heterostructure changes \Rightarrow Optoelectronic properties of the heterostructure change.
- “Al” atoms segregated in AlGaSb/GaSb QW.



How can we characterize the segregation?

- Experimental measurements:
 - Reflection High Energy Electron Diffraction (RHEED).
 - Rutherford Backscattering Spectroscopy (RBS).
 - Electron Energy Loss Spectroscopy (EELS).
 - Secondary Ion Mass Spectroscopy (SIMS).
 - High Resolution X-ray Diffraction (HRXRD).
 - X-ray Photoelectron Spectroscopy (XPS).
 - UV Photoelectron Spectroscopy (UPS).
 - Auger Electron Spectroscopy (AES).
 - Photoluminescence (PL).
 - Raman Spectra (RS).
 - High Resolution Transmission Electron Microscopy (HRTEM).
 - Etc.



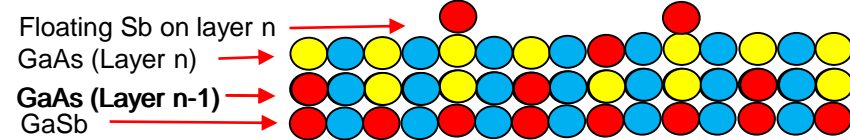
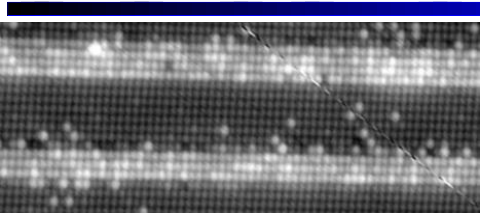
Segregation Theoretical Models

- 1) Muraki's Model
- 2) Sigmoidal
- 3) Kinetics Model
- 4) Sigmoidal Model
- 5) Fluid Three-layer Exchange Model
- 6) Kinetics Monte Carlo Simulation(KMC)



1) Muraki's Model

Sb Segregation with **no** Sb Background Gas



- **No Background Gas:** تعداد اتمهای Sb که در لایه n قرار دارند برابر هستند با R درصد از اتمهای n-1.

$$x_f^n = R x_f^{n-1} \quad (\text{Eq-1})$$

- تعداد اتمهایی که لایه n را تشکیل می دهند (x_{inc}^n) برابر هستند با:

$$x_f^{n-1} - x_f^n = x_{inc}^n \quad (\text{Eq-2})$$

$$(\text{Eq-1, 2}) \Rightarrow x_{inc}^n = x_f^{n-1} - R x_f^{n-1} = x_f^{n-1} (1 - R) \quad (\text{Eq-3})$$

- In which, “ X_f ” is the floating “Sb”, “R” is the segregation ratio of the previous antimony into the next layer, “ X_{inc} ” is the “Sb” that incorporated to epitaxial growth.

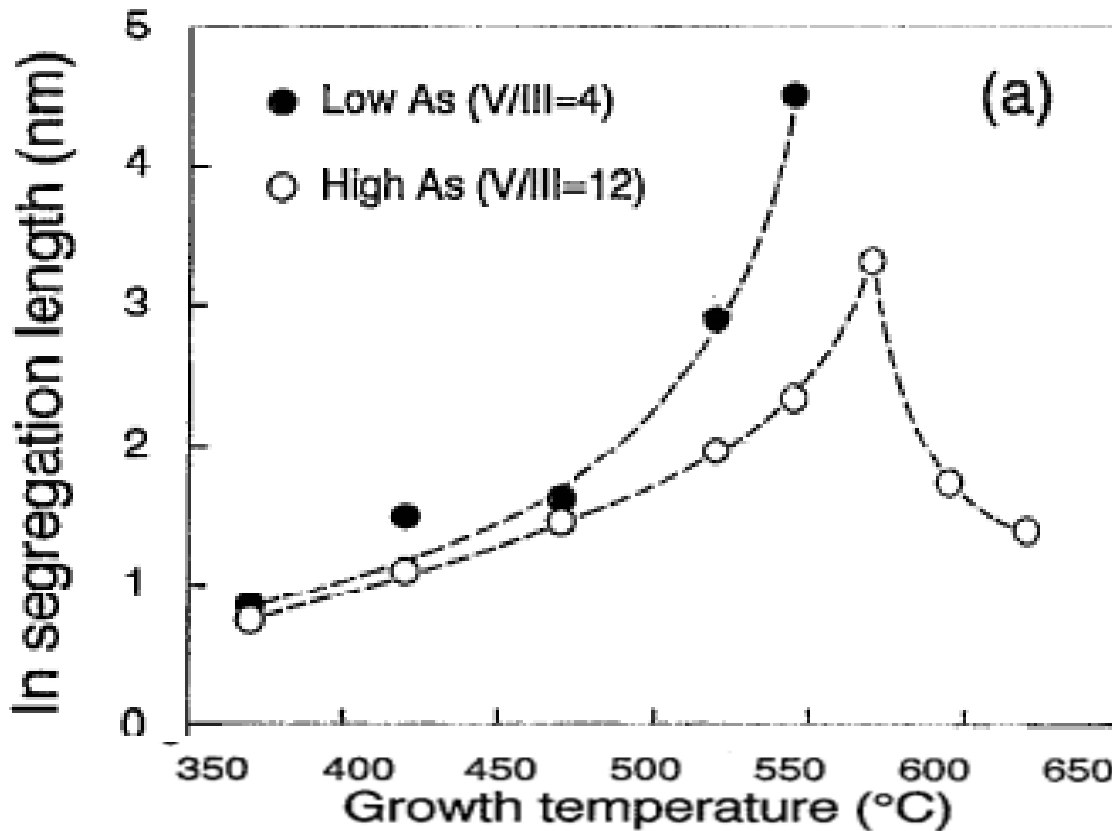
Sb Segregation with no Sb Background Gas

- In general we have:

$$R = e^{-\frac{d}{\lambda}}$$

- In which “d” is half the lattice constant, “λ” is the segregation length which can be obtained from SIMS profile.
- R for different material of group III can be found in PRB_40_6149.

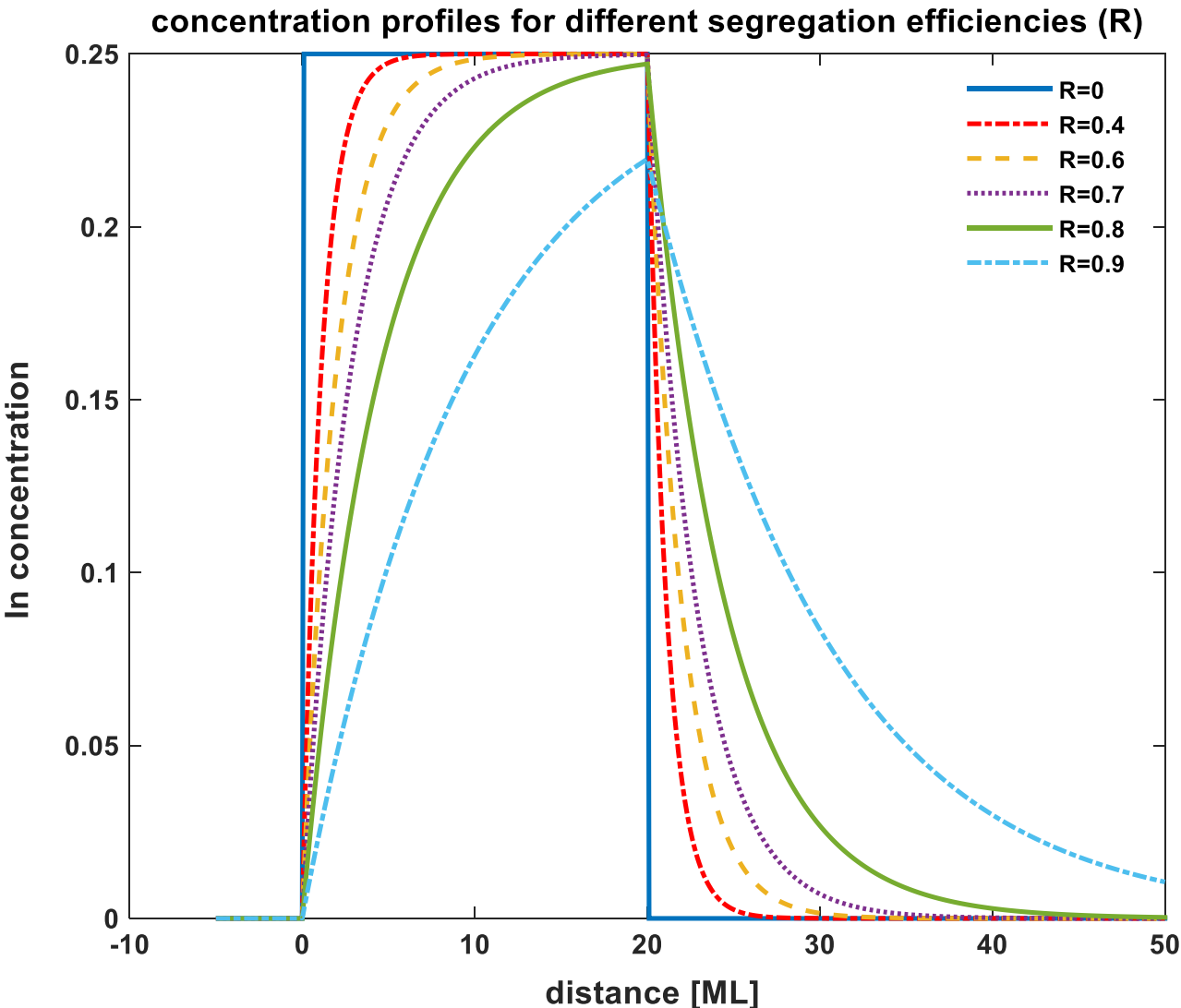
Supporting Length



وابستگی طول مهاجرت In به سطح به دمای رشد

- وابستگی طول مهاجرت In در سطح به دمای رشد بدست آمده از SIMS در شکل مقابل خلاصه شده است.
- طول تفکیک با کاهش دمای رشد، کاهش میابد. این امر به این دلیل است که تفکیک سطح، به عبارت دیگر، تبادل اتم بین سطح و فاز bulk از نظر جنبشی با کاهش دما محدود می شود.

"R" Effect on Supporting Length



پروفایل های تمرکز In برای بازدهی های segregation مختلف

- پروفایل تمرکز In از چاه کوانتومی برای ساختار نامتناجس InGaAs/GaAs بازدهی های مهاجرت مختلف با استفاده از مدل موراکی و نرم افزار MATLAB شبیه سازی شده و در شکل مقابل نشان داده شده است.
- همان طور که مشاهده میشود هرچه قدر مقدار R بیشتر باشد اتم ها در طول بیشتری در لایه بعدی مهاجرت میکنند.

Sb Segregation with Sb Background Gas

- When we have Sb background Gas, Eq-1 become:

$$x_f^n = R (x_f^{n-1} + x_o) \quad (\text{Eq-4})$$

x_o = The excessive Sb from the background pressure.

$$(x_f^{n-1} + x_o) - (Rx_f^{n-1} + Rx_o) = x_{inc}^n \quad (\text{Eq-5})$$

{ Floating Sb on layer n-1
 { The segregated Sb from n-1 to n layer

$$x_{inc}^n = x_f^{n-1} - Rx_f^{n-1} + x_o - Rx_o = x_f^{n-1} (1 - R) + x_o (1 - R) \quad (\text{Eq-6})$$

$$x_{inc}^n = (1 - R)(x_f^{n-1} + x_o) \quad (\text{Eq-7})$$

Sb Segregation with Sb Background Gas

- From Eq-4 we have: $x_f^n = R (x_f^{n-1} + x_o)$ therefore:

$$x_f^0 \equiv x_i$$

$$x_f^1 = R (x_f^0 + x_o) = R (x_i + x_o) = Rx_i + Rx_o$$

$$\begin{aligned} x_f^2 &= R (x_f^1 + x_o) = R [(Rx_i + Rx_o) + x_o] = R^2 x_i + R^2 x_o + Rx_o \\ &= R^2 x_i + x_o R(R + 1) \end{aligned}$$

$$\begin{aligned} x_f^3 &= R (x_f^2 + x_o) = R [(R^2 x_i + x_o R(R + 1)) + x_o] \\ &= R^3 x_i + x_o R(R^2 + R + 1) \end{aligned}$$

$$x_f^n = R^n x_i + x_o R(R^{n-1} + R^{n-2} + \dots + R + 1) \quad (\text{Eq-8})$$

- بخشی از رابطه ی فوق $(R^3 + R^2 + R + 1)$ یک سری هندسی است، با مقدار اولیه 1 و قدر نسبت R
- از این سری هندسی داریم:

$$\sum_{k=0}^n ar^k = ar^0 + ar^1 + ar^2 + ar^3 + \dots + ar^n = \frac{a(1 - r^{n+1})}{1 - r}. \quad (\text{Eq-9})$$

Sb Segregation with Sb Background Gas

- From Eq-8 and 9:

$$x_f^n = R^n x_i + x_o R \frac{1 - R^{n+1}}{1 - R} \quad \text{يا} \quad x_f^{n-1} = R^{n-1} x_i + x_o R \frac{1 - R^n}{1 - R} \quad (\text{Eq-10})$$

- From Eq-7 and 10:

$$\begin{aligned} x_{inc}^n &= (1 - R)(x_f^{n-1} + x_o) = (1 - R) \left(R^{n-1} x_i + x_o R \frac{1 - R^n}{1 - R} + x_o \right) \\ &= (1 - R) R^{n-1} x_i + x_o R (1 - R^n) + x_o (1 - R) \\ &= x_i R^{n-1} (1 - R) + x_o R - x_o R^n + x_o - x_o R \end{aligned}$$

$$x_{inc}^n = \underbrace{x_i R^{n-1} (1 - R)}_{\text{Sb Falloff}} + \underbrace{x_o (1 - R^n)}_{\text{Sb Background Incorporation}} \quad (\text{Eq-11})$$



Muraki's Model Examples

Sb Segregation in Type II SLS

$$x^{Sb}(n) = x_i^{Sb} R^{n-1} (1 - R) + x_o^{Sb} (1 - R^n)$$

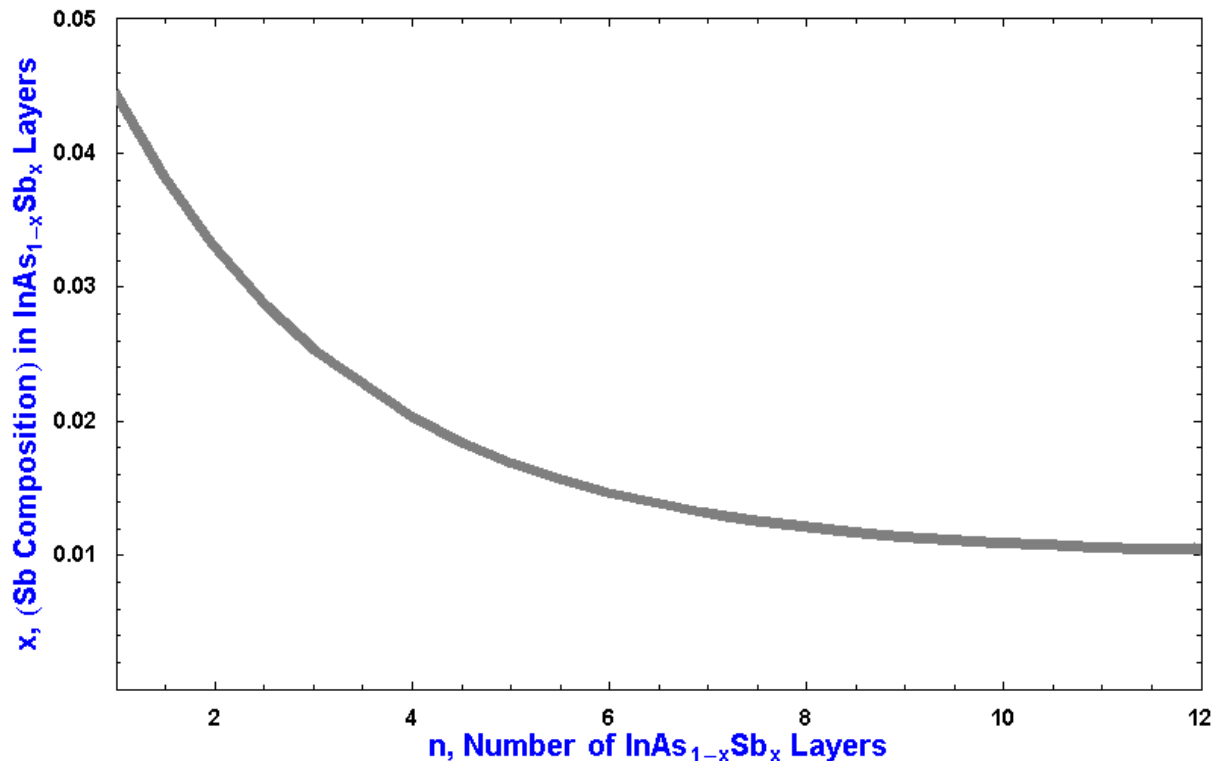
$x^{Sb}(n)$ = The Sb Composition at the n^{th} layer of the InAs.

x_i^{Sb} = An initial impurity fraction on the finished GaSb.

x_o^{Sb} = The excessive Sb from the background pressure.

R = The segregation ratio of the previous antimony into the next layer .

- “Sb” Incorporation “x” for GaSb/InAs SLS at 400°C with $x_i^{Sb}=0.124$, $x_o^{Sb}=0.010$, and $R=0.67$.



In Segregation in Type II SLS

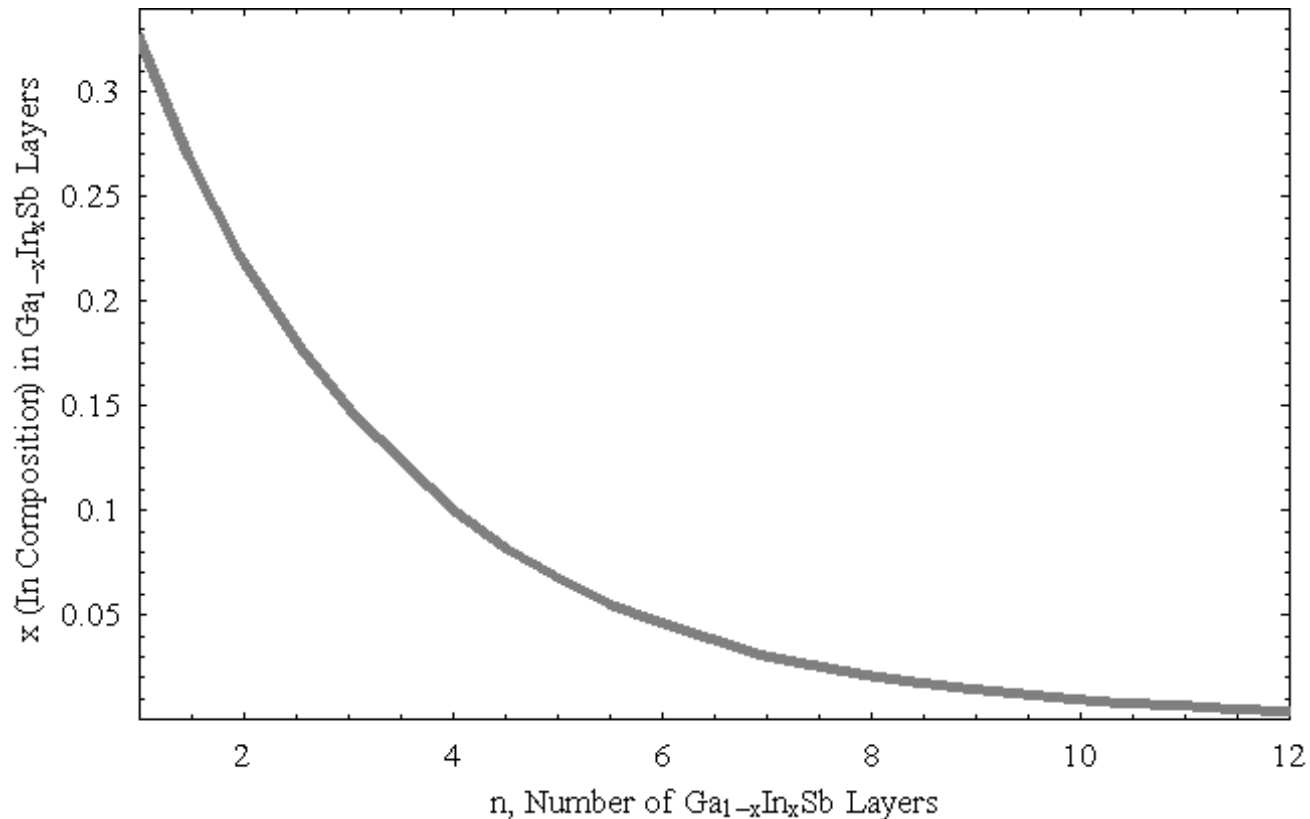
$x^{\text{In}}(n)$ = In Composition at the n^{th} layer of the GaSb.

x_i^{In} = The nominal In Composition on the Seed layer.

R = The segregation ratio of the previous layer to the next layer.

$$x^{\text{In}}(n) = x_i^{\text{In}} R^{n-1} (1 - R)$$

- In Incorporation “x” for **GaSb/InAs** SLS at 400°C with $x_i^{\text{In}}=1.0$, and $R=0.66$.



- In Segregation can be detected by RHEED

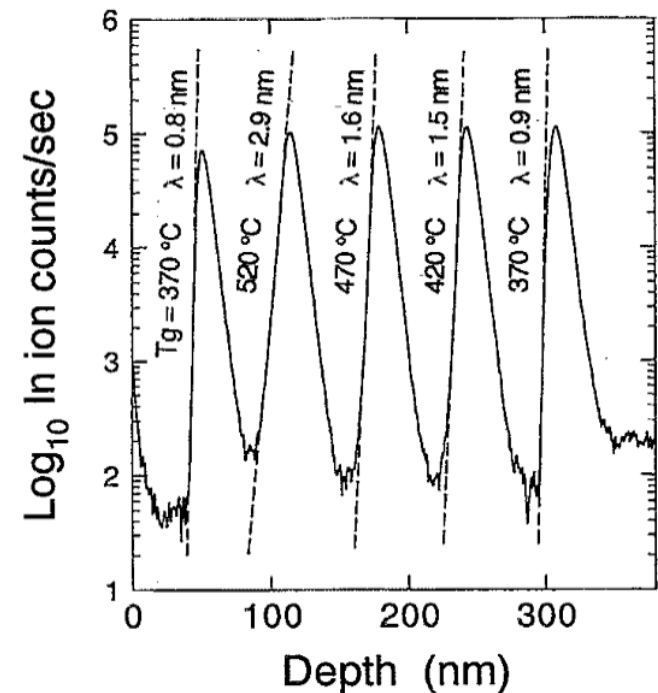
Muraki's Model for In Segregation

- System: $\text{In}_x\text{Ga}_{1-x}\text{As}/\text{GaAs}$
 - $R=0.91$ at $T=520(^{\circ}\text{C})$
 - $R=0.70$ at $T=370(^{\circ}\text{C})$

$$R = e^{-\frac{d}{\lambda}}$$

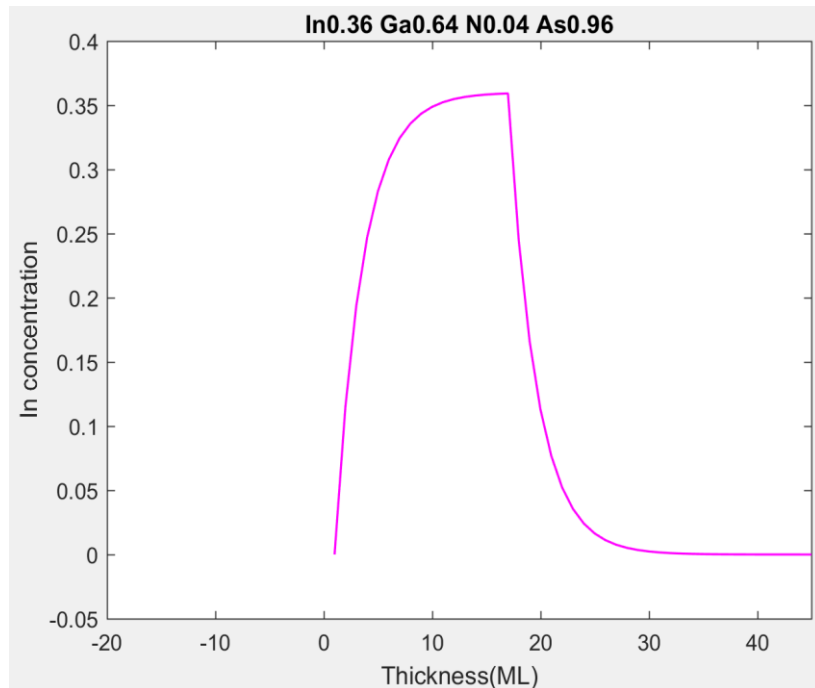
- In which “d” is half the lattice constant of GaAs (2.83 \AA), “ λ ” is the segregation length which can be obtained from SIMS profile

temperature($^{\circ}\text{C}$)	370	420	470	520
R	0.70	0.82	0.83	0.91

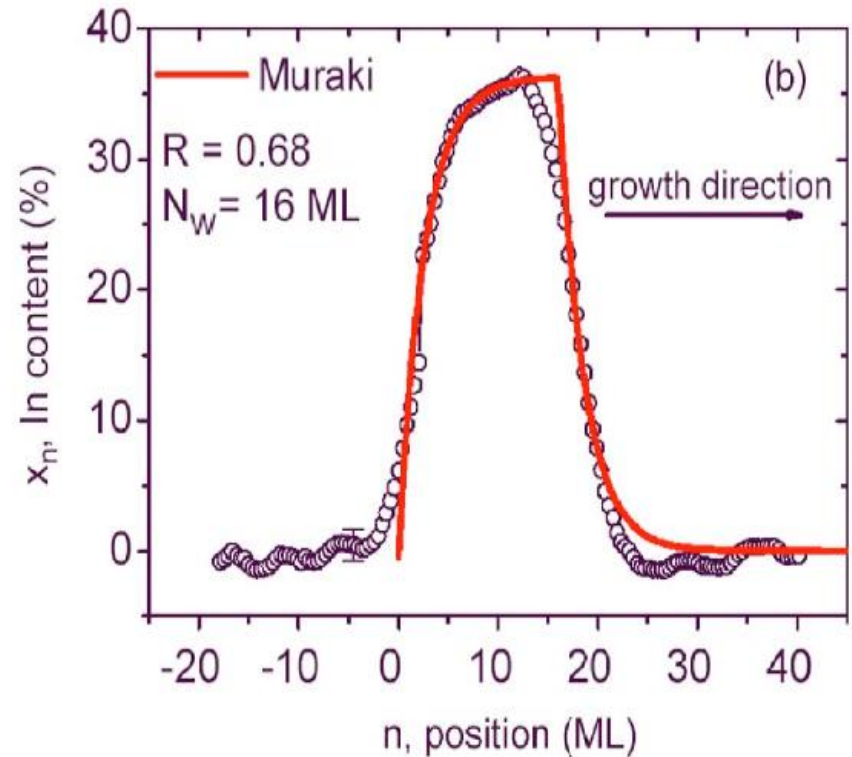


Muraki's Model for In Segregation

System: $\text{In}_{0.36} \text{Ga}_{0.64} \text{N}_{0.04} \text{As}_{0.96} / \text{GaAs}$



Mr. Mokhtari's Simulation





2) Sigmoidal Model

Sigmoidal Model

- In 2008, a new model was introduced by Luna which helped Muraki's model to fit better the experimental data. APL_2_141913

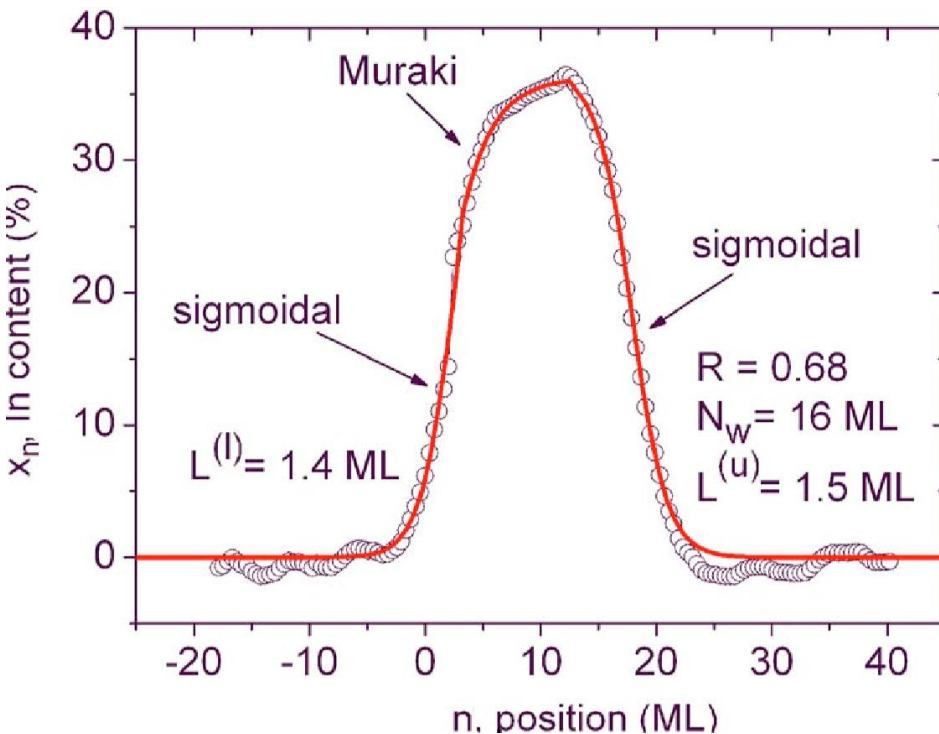
معادلات Sigmoidal

$$x_n = \frac{x_0^{(l)}}{1 + e^{-(n + \frac{N_w}{2})/L^{(l)}}}$$

for $n < 0$ (Lower Interface)

$$x_n = x_0^{(u)} - \frac{x_0^{(u)}}{1 + e^{-(n - \frac{N_w}{2})/L^{(u)}}}$$

for $n > 0$ (Upper Interface)



- در این معادلات x_n همان معنا را در معادلات موراکی دارد و N_w تعداد لایه های Well است.
- $L^{(l)}$ و $L^{(u)}$ دو پارامتر هستند که به کمک تطبیق باید اندازه گرفته شوند و محل تفاوت مدل موراکی و سیگموئیدال است.
- $x_0^{(l)}$ و $x_0^{(u)}$ درصد اتم های ایندیوم در محل تغییر بالا و پایین است.